

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

ATENT AND TRADEMARK OFFICE

JUN 28 2002

Applicant : Alan Wong et al.  
 Serial No. : 10/083,877  
 Filed : February 25, 2002  
 Title : OPTICAL METRIC MEASUREMENT

Art Unit : 2811  
 Examiner : Unknown

TARGET DESIGN FOR SIMULTANEOUS  
MULTIPLE PERIODIC STRUCTURES

Commissioner for Patents  
 Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

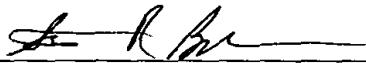
Applicant submits the references listed on the attached form PTO-1449, copies of which are enclosed.

This statement is being filed before the receipt of a first Office action on the merits.

Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 6/28/02

  
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U.S. Patent and Trademark Office Form PTO-1449 Information Disclosure Statement by Applicant 128 2002 (37 CFR §1.56(b))	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-591001	Application No. 10/083,877
		Applicant Alan Wong et al.	
		Filing Date February 25, 2002	Group Art Unit

U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						

Foreign Patent Documents or Published Foreign Patent Applications							
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation Yes No
	AB						

Other Documents (include Author, Title, Date, and Place of Publication)							
Examiner Initial	Desig. ID	Document					
	AC	International Technology Roadmap for Semiconductors 2000 Update, "Metrology", pages 1-12.					
	AD	International Technology Roadmap for Semiconductors 2000 Update, "Overall Roadmap Technology Characteristics", pages 1-32.					
	AE	International Technology Roadmap for Semiconductors 1999 Edition, "Metrology", pages 295-313.					
	AF	International Technology Roadmap for Semiconductors 1999 Edition, "Introduction", pages 1-22.					
	AG	International Technology Roadmap for Semiconductors 1999 Edition, "Overall Roadmap Technology Characteristics and Glossary", pages 1-22.					
	AH	International Technology Roadmap for Semiconductors, "On-Line ITRS Documents", 3 pages: <a href="http://public.itrs.net/Reports.htm">http://public.itrs.net/Reports.htm</a> , last updated June 4, 2001 (printed 10/26/2001), <a href="http://public.itrs.net/Files/2000UpdateFinal/2kUdFinal.htm">http://public.itrs.net/Files/2000UpdateFinal/2kUdFinal.htm</a> , last updated December 15, 2000 (printed 10/26/2001), <a href="http://public.itrs.net/Files/1999_SIA_Roadmap/Home.htm">http://public.itrs.net/Files/1999_SIA_Roadmap/Home.htm</a> , (printed 10/26/2001).					
	AI	"EEEL, OMP, Optical-Based Dimensional Metrology", 8 pages, <a href="http://www.eeel.nist.gov/omp/dimension_optical.html">http://www.eeel.nist.gov/omp/dimension_optical.html</a> , dated June 12, 2001 (printed 10/22/2001).					
	AJ	"EEEL, OMP, Critical Dimension and Overlay Metrology Program", 1 page, <a href="http://www.eeel.nist.gov/omp/dimension.html">http://www.eeel.nist.gov/omp/dimension.html</a> , dated June 12, 2001 (printed 10/22/2001).					
	AK	"Nanotechnology", 8 pages, <a href="http://www.eeel.nist.gov/812/nano.html">http://www.eeel.nist.gov/812/nano.html</a> , (printed 10/22/2001).					
	AL	"EEEL, OMP, Electrical-Based Dimensional Metrology", 7 pages, <a href="http://www.eeel.nist.gov/810.01/dimension_electrical.html">http://www.eeel.nist.gov/810.01/dimension_electrical.html</a> , dated June 12, 2002 (printed 10/22/2001).					
	AM	"The Fundamentals of Overlay Metrology", 4 pages, <a href="http://www.e-insite.net/semiconductor/index.asp?layout=articlePrint&amp;articleID=CA159008">http://www.e-insite.net/semiconductor/index.asp?layout=articlePrint&amp;articleID=CA159008</a> , dated 9/1/2002 (printed 01/21/2002).					
	AN	International Technology Roadmap for Semiconductors 2001 Edition, "Executive Summary", pages 1-57.					
	AO	International Technology Roadmap for Semiconductors 2001 Edition, "Metrology", pages 1-24.					
	AP	"2001 ITRS Home Page", 2 pages, <a href="http://public.itrs.net/Files/2001ITRS/Home.htm">http://public.itrs.net/Files/2001ITRS/Home.htm</a> , (printed 01/21/2002).					
	AQ	"The Fundamentals of Overlay Metrology - SI September 2001", 6 pages, <a href="http://www.google.com/search?q=cache:ofSQhAFmV6UC:209.67.253.149/semiconductor">http://www.google.com/search?q=cache:ofSQhAFmV6UC:209.67.253.149/semiconductor</a> , (printed 01/21/2002).					

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	